*Electronic supplementary information* 

## Modulating oxygen vacancies in Sn-doped hematite film grown on silicon microwires for

## photoelectrochemical water oxidation

Zhongyuan Zhou,<sup>a,b</sup> Shaolong Wu,\* a,b Linling Qin,<sup>a,b</sup> Liang Li,<sup>a,b</sup> Liujing Li<sup>a,b</sup> and Xiaofeng Li\*a,b

<sup>a</sup> School of Optoelectronic Science and Engineering & Collaborative Innovation Center of Suzhou Nano Science and Technology, Soochow University, Suzhou 215006, China

<sup>b</sup> Key Lab of Advanced Optical Manufacturing Technologies of Jiangsu Province & Key Lab of Modern Optical Technologies of Education Ministry of China, Soochow University, Suzhou 215006, China

\*Correspondence

Dr. Shaolong Wu; Prof. Xiaofeng Li

E-mail: shaolong\_wu@suda.edu.cn; xfli@suda.edu.cn

Name	Molecular formula	Specification		
Silicon	Si	N (100), $\rho$ (0.01-0.02 Ωcm)		
Acetone	CH <sub>3</sub> COCH <sub>3</sub>	> 99.5%		
Ethanol	CH <sub>3</sub> CH <sub>2</sub> OH	> 99.7%		
Deionized water	H <sub>2</sub> O	$\rho \geq 18.25 \; \Omega m$		
Sulfuric acid	$H_2SO_4$	95.0% ~ 98.0%		
Hydrogen peroxide	$H_2O_2$	AR, $\geq 30\%$		
Hydrofluoric acid	HF	AR, $\geq$ 40%		
Silver nitrate	AgNO <sub>3</sub>	AR, $\geq$ 99.8		
Nitric acid	HNO <sub>3</sub>	AR, 65.0% ~ 68.0%		
Ferric Nitrate	Fe(NO <sub>3</sub> ) <sub>3</sub> ·9H <sub>2</sub> O	AR, ≥ 99.99%		
Stannic Chloride	$SnCl_4 \cdot 5H_2O$	$AR, \geq 98\%$		
Silica gel		NanDa 703		
Developing solution		RZX-3038		
Photoresist	_	RZJ-304		

 Table S1 Reagents and related experimental materials are employed in the experiment.



**Fig. S1** (a) The normal thermal process for synthesizing the hematite; (b) the post-heating process with RTP for modifying the hematite.

**Table S2.** A comparison of the PEC performances between the typical hematite/silicon (and hematite) photoanodes in the related literatures and our present  $\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiMWs photoanode.

Photoanode	Film texture	Optimized sample ( <i>J-V</i> curves)	J <sub>ph@1.23V</sub> U <sub>on</sub>	Testing conditions (under AM 1.5G irradiation)	Key Method	Ref.
α-Fe <sub>2</sub> O <sub>3</sub> /n-SiNWs	а в <i>Род.</i> 1 1 5 µm	b) 12 10 10 10 10 10 10 10 10 10 10	0.90 mA/cm <sup>2</sup> 0.60 V <sub>RHE</sub>	1 M NaOH	atomic layer deposition	[1]
α-Fe <sub>2</sub> O <sub>3</sub> /n-SiNWs		Current of the second of the s	5.28 mA/cm <sup>2</sup> 0.50 V <sub>RHE</sub>	1 M NaOH (scan rate 50 mV/s) with magnetic stirring	deposition annealing	[2]
α-Fe <sub>2</sub> O <sub>3</sub> /n-SiNWs decorated with AuNPs	<u>зи</u> <u>5 µт</u>	a 	2.56 mA/cm <sup>2</sup> at 0 V vs. Pt mesh	1 M NaOH two-electrode cell	deposition annealing	[3]
Sn@α-Fe <sub>2</sub> O <sub>3</sub> / SiMWs with RTP	е. с с 1 пл 20 пл 10 пл 1	0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0 0	3.12 mA/cm <sup>2</sup> 0.15 V <sub>RHE</sub>	1 M NaOH (scan rate 20 mV/s)	Sn doping and RTP at 400 °C for 5 min	This work
Fe <sub>2</sub> TiO <sub>5</sub> /Fe <sub>2</sub> O <sub>3</sub> / ITO/FTO with OER catalyst		$ \begin{array}{c} 25 \\ \hline \\ 0 \\ 0 \\ 0 \\ 0 \\ 0 \\ 0 \\ 0 \\ 0 \\ 0$	2.20 mA/cm <sup>2</sup> 0.95 V <sub>RHE</sub>	1 M NaOH purged with N <sub>2</sub> (scan rate 20 mV/s)	hydrothermal photoelectron- deposition, ALD, hydrothermal, sputtering	[4]
Pt-doped hematite with Co-Pi	- 100 X70.000 - 100nm	Current de la construir de la	4.32 mA/cm <sup>2</sup> 0.50 V <sub>RHE</sub>	1 M NaOH	in-situ two-step annealing at 550 °C and 800 °C of FeOOH nanorods	[5]
α-Fe <sub>2</sub> O <sub>3</sub> /FTO	c) N-hematite	A-hematile A-hema	1.82 mA/cm <sup>2</sup> 1.0 V <sub>RHE</sub>	1 M NaOH (scan rate 10 mV/s)	sintered in an oxygen-deficient atmosphere (N <sub>2</sub> +air) at 550 °C for 2 h	[6]



**Table S3.** A summary of the Mott-Schottky performance of the pristine SiMWs, the  $\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/FTO and the four modified  $\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiMWs hybrids.

Samples	$N_{\rm D}~({\rm cm}^{-3})$	$U_{\mathbf{fb}}$ (V <sub>RHE</sub> )
SiMWs	1.64×10 <sup>18</sup>	0.68
α-Fe <sub>2</sub> O <sub>3</sub> /FTO	2.09×10 <sup>19</sup>	0.53
α-Fe <sub>2</sub> O <sub>3</sub> /SiMWs	2.01×10 <sup>18</sup>	0.91
$Sn@\alpha$ -Fe <sub>2</sub> O <sub>3</sub> /SiMWs	3.98×10 <sup>18</sup>	0.89
$\alpha$ -Fe <sub>2</sub> O <sub>3</sub> /SiMWs with RTP	6.32×10 <sup>18</sup>	0.87
$Sn@\alpha$ -Fe <sub>2</sub> O <sub>3</sub> /SiMWs with RTP	1.92×10 <sup>19</sup>	0.84

**Table S4.** The fitting EIS data of the  $\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiMWs with various treatments based on equivalent circuits.

Sample	$R_{\rm S}(\Omega)$	$R_{\rm CT}(\Omega)$	$C_{\rm SC}({\rm F})$
α-Fe <sub>2</sub> O <sub>3</sub> /SiMWs	63.86	545.8	2.34×10 <sup>-8</sup>
Sn@a-Fe <sub>2</sub> O <sub>3</sub> /SiMWs	19.19	257	1.18×10 <sup>-8</sup>
α-Fe <sub>2</sub> O <sub>3</sub> /SiMWs with RTP	18.17	65.38	8.09×10 <sup>-8</sup>
Sn@α-Fe <sub>2</sub> O <sub>3</sub> /SiMWs with RTP	10.74	13.87	4.81×10 <sup>-7</sup>



**Fig. S2** (a–d) Typical SEM images of the freshly as-prepared SiMWs. (a) and (b) are the top view and cross-sectional image, respectively. (c) and (d) are the detail view of the top and the side, respectively.



Fig. S3 TEM image of the uniform hematite film conformally grown on SiMWs.



**Fig. S4** Raman spectra of the  $\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiMWs. The five peaks (225 cm<sup>-1</sup>, 291 cm<sup>-1</sup>, 409 cm<sup>-1</sup>, 498 cm<sup>-1</sup> and 610 cm<sup>-1</sup>) are correspond to the standard peaks of  $\alpha$ -Fe<sub>2</sub>O<sub>3</sub>. The peak at 523 cm<sup>-1</sup> is from the Si (distinguished by \*), and the last peak at 662 cm<sup>-1</sup> is assigned to the presence of Fe<sub>3</sub>O<sub>4</sub>, due to that FeO are not stable at room temperature.



Fig. S5 SEM (a) and EDS spectrum (b) of the  $Sn@\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiMWs recorded in the red box in (a).



**Fig. S6** XPS spectra of the Sn@ $\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiMWs. In (b), the peaks at 724.7 eV and 710.9 eV are ascribed to the Fe 2p<sub>1/2</sub> and Fe 2p<sub>3/2</sub>, indicating the typical values of Fe<sup>3+</sup> in Fe<sub>2</sub>O<sub>3</sub>. In (c) the Sn 3d<sub>5/2</sub> (486.1 eV) and Sn 3d<sub>3/2</sub> (494.6 eV) indicate that the Sn exists in the Sn@ $\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiMWs. In (d), two peaks at 529.9 eV and 532.4 eV are assigned to iron oxide lattice (Fe-O) and hydroxyl groups (Fe-OH adsorbed), respectively.



Fig. S7 SEM image of the  $\alpha$ -Fe<sub>2</sub>O<sub>3</sub> grown on the FTO substrate (a) and the corresponding XRD pattern (b).



**Fig. S8** Photoelectrochemical properties of the  $\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/FTO (a, b) and the bare SiMWs (c, d). (a and c) are the *J*-*V* curves. (b and d) are the Mott-Schottky plots.



Fig. S9 IPCE spectra of the Sn@ $\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiMWs with RTP under 0.5 V bias between the photoanode and Pt electrode (i.e., the applied potential is calculated to be ~1.3 V<sub>RHE</sub> according to the Nernst equation).



Fig. S10 The applied bias photon-to-current efficiency (ABPE) of the  $Sn@\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiMWs with RTP.



**Fig. S11** (a) *J-V* curves of the Sn@ $\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiMWs with RTP after PEC measurement for different operation time; (b) SEM images of the Sn@ $\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiMWs with RTP after PEC testing for 1 h.



Fig. S12 XPS spectra of the Sn@α-Fe<sub>2</sub>O<sub>3</sub>/SiMWs with RTP before PEC test and after PEC test.



Fig. S13 The employed system for H<sub>2</sub> and O<sub>2</sub> evolution amount from a PEC cell.



**Fig. S14** (a) Photocurrent density vs. time (*I-t*) curve of the  $Sn@\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiMWs with RTP, the curve was obtained under simulated AM 1.5 G illumination at potential of 1.23 V vs. RHE in 1.0 M NaOH electrolyte. (b) Gas evolution amount and the calculated Faradaic efficiency.



Fig. S15 *J-V* curves of the Sn@ $\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiMWs with RTP using (a) heavily n-doped (0.01–0.02  $\Omega$ cm) and (b) lightly n-doped Si (1–10  $\Omega$ cm) substrates.



Fig. S16 Reflectance spectra of the polished Si, the bare SiMWs, the  $Sn@\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiMWs and the bare disordered Si nanowires (as shown in the inset SEM image) for using as a reference.



Fig. S17 SEM images of the prepared  $\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiNWs (a) top-view, (b) cross-section and (c) the detail view of the side; (d) *J-V* curves of the Sn@ $\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiMWs with RTP and the Sn@ $\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiNWs with RTP in the dark and under simulated AM 1.5G irradiation.



Fig. S18 The contrastive patterns of Raman of the Sn-doped and undoped  $\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiMWs without RTP (peaks indicated by \* are from Si).



Fig. S19 The XPS contrastive plots of the Sn-doped and undoped  $\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiMWs photoanode.



Fig. S20 Mott-Schottky plots of the  $Sn@\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiMWs with RTP at different temperatures.



Fig. S21 The XRD patterns of the  $Sn@\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiMWs with RTP at different temperatures.



Fig. S22 EDS comparison for the undoped  $\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiMWs without RTP (a), the Sn-doped  $\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiMWs without RTP (b), and the Sn-doped  $\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiMWs with RTP at different temperatures (c–f), respectively.



Fig. S23 EDS comparison for the Sn@ $\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiMWs without RTP (a), RTP at 400 °C (b) and RTP at 800 °C (c), respectively.



Fig. S24 The contrastive SEM images of the  $Sn@\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiMWs with RTP at different temperatures.



Fig. S25 HRTEM analysis of the synthesized Sn-doped  $\alpha$ -Fe<sub>2</sub>O<sub>3</sub> without RTP (a and b), with RTP at 400 °C (c and d) and RTP at 800 °C (e and f).



**Fig. S26** The XPS spectra of (a) survey, (b) Sn 3d, (c) N 1s and (d) normalized XPS O1s peak of the  $Sn@\alpha$ -Fe<sub>2</sub>O<sub>3</sub>/SiMWs with RTP at different temperatures.

## References

- [1] M. T. Mayer, C. Du and D. Wang, J. Am. Chem. Soc., 2012, 134, 12406–12409.
- [2] X. Qi, G. She, X. Huang, T. Zhang, H. Wang, L. Mu and W. Shi, *Nanoscale*, 2014, 6, 3182– 3189.
- [3] X. Wang, K.-Q. Peng, Y. Hu, F. Q. Zhang, B. Hu, L. Li, M. Wang, X. M. Meng and S. T. Lee, *Nano Lett.*, 2014, 14, 18–23.
- P. Tang, H. Xie, C. Ros, L. Han, M. B. Peiro, Y. He, W. Kramer, A. P. Rodriguez, E. Saucedo, J. R. G. Mascaros, T. Andreu, J.R. Morante and J. Arbiol, *Energy Environ. Sci.*, 2017, 10, 2124–2136.
- [5] J. Y. Kim, G. Magesh, D. H. Youn, J. W. Jang, J. Kubota, K. Domen and J. S. Lee, *Sci. Rep.*, 2013, 3, 2681.
- [6] Y. Ling, G. Wang, J. Reddy, C. Wang, J. Zhang and Y. Li, Angew. Chem. Int. Ed., 2012, 51, 4074–4079.
- [7] C. Zhu, C. Li, M. Zheng and J. J. Delaunay, ACS Appl. Mater. Interfaces, 2015, 7, 22355–22363.
- [8] J. J. Wang, Y. Hu, R. Toth, G.Fortunato and A. Braun, J. Mater. Chem. A., 2016, 4, 2821–2825.
- [9] A. N. Bondarchuk, L. M. Peter, G. P. Kissling, E. Madrid, J. A. Aguilar-Martinez, Z. Rymansaib, P. Iravani, M. Gromboni, L. H. Mascaro, A. Walsh, F. Marken, *Appl. Catal. B-Environ.*, 2017, 211, 289–295.